

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re the application of:

TSUCHIYA et al.

Art Unit: Not yet assigned

Serial Number: New Divisional Application

Examiner: Not yet assigned

Filed: November 5, 2003

Attorney Dkt. No. 107242-00031

For: WAFER ROTARY HOLDING APPARATUS AND WAFER SURFACE  
TREATMENT APPARATUS WITH WASTE LIQUID RECOVERY MECHANISM

**PRELIMINARY AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450  
Sir:

Date: November 5, 2003

This is a Preliminary Amendment for the above-identified Divisional application, filed concurrently herewith. Prior to initial examination of the application, please amend the above-identified Divisional application as shown on the following pages: